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Att. Docket No. 10191/1690

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. : 09/762,985 Confirmation No. 2674
Title : DEVICE AND METHOD FOR
ETCHING A SUBSTRATE USING
AN INDUCTIVELY COUPLED PLASMA

Applicant(s) : Volker BECKER et al.
Filed : May 8, 2001
TC/A.U. : 1763
Examiner : Luz L Alejandro Mulero
Docket No. : 10191/1690
Customer No. : 26646

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Commissioner for Patents
P.O. Box 1450
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Signature: [Signature]
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TRANSMITTAL AND PETITION TO EXTEND

SIR:

Please find transmitted herewith for filing in the above-identified patent application is an Amendment After A Final Office Action.

Applicants request a two-month extension of time to respond to the Final Office Action dated August 23, 2006 from the three-month response date of November 23, 2006 to January 23, 2007. The extension fee of \$450.00 or any additional fees should be charged (or credited, as necessary) to Kenyon & Kenyon LLP, **Deposit Account No. 11-0600**. Two duplicate copies of this transmittal letter are enclosed for these purposes.

Dated: 1/19/2007

Respectfully submitted,

By: [Signature]

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